## **AMENDMENTS TO THE CLAIMS:**

## Complete Claim Listing:

1. (Currently Amended) A method for forming a semiconductor device, comprising:

providing a package device having a first heat spreader, a package substrate overlying the
first heat spreader, and a cavity extending through the package substrate and into
the first heat spreader;

attaching a first die to the first heat spreader within the cavity;

attaching a second heat spreader to the first die;

forming a plurality of electrical wire bond connections between the first die and the package substrate; and

encapsulating the electrical connections, the first die, and at least a portion of the second heat spreader.

- 2. (Canceled).
- 3. (Original) The method of claim 1, further comprising:
  after attaching the first die to the first heat spreader, attaching a second die to the first die,
  wherein the second heat spreader is attached to the second die.
- 4. (Original) The method of claim 3, further comprising: forming a plurality of electrical connections between the second die and the package substrate.

and wherein encapsulating further comprises encapsulating the second die.

- 5. (Original) The method of claim 4, further comprising forming at least one electrical connection between the second heat spreader and at least one of the first or the second die.
- 6. (Original) The method of claim 1, further comprising forming at least one electrical connection between the second heat spreader and the first die.

- 7. (Currently Amended) A semiconductor device, comprising:
  - a first heat spreader;
  - a cavity extending into the first heat spreader,
  - a first semiconductor die within the cavity and attached to the first heat spreader; and
  - a second heat spreader overlying the first semiconductor die, a die attach material being used to connect the first semiconductor die to the second heat spreader.
- 8. (Original) The semiconductor device of claim 7, further comprising a package substrate overlying the first heat spreader, wherein the cavity extends through the package substrate.
- 9. (Original) The semiconductor device of claim 8, further comprising a plurality of solder balls overlying the package substrate.
- 10. (Original) The semiconductor device of claim 8, further comprising a plurality of electrical connections between the first semiconductor die and the package substrate.
- 11. (Original) The semiconductor device of claim 10, further comprising an encapsulation layer encapsulating the plurality of electrical connections, the first semiconductor die, and at least a portion of the second heat spreader.
- 12. (Original) The semiconductor device of claim 7, further comprising:
  a second semiconductor die within the cavity, overlying the first semiconductor die and underlying the second heat spreader.
- 13. (Original) The semiconductor device of claim 12, wherein the second heat spreader is connected to the second semiconductor die via a first die attach and the second semiconductor die is connected to the first semiconductor via a second die attach.
- 14. (Canceled).

- 15. (Original) The semiconductor device of claim 7, wherein the second heat spreader is soldered to a metal layer overlying the first semiconductor die.
- 16. (Original) The semiconductor device of claim 7, wherein the second heat spreader comprises a first portion and a second portion, the first portion closer to the first semiconductor die than the second portion, and wherein the first portion has a first surface area and the second portion has a second surface area that is less than the first surface area.
- 17. (Original) The semiconductor device of claim 16, wherein the first portion and the second portion are contiguous portions of the second heat spreader.
- 18. The semiconductor device of claim 16, further comprising:

  an electrical connection coupled to the first portion of the second heat spreader and the first semiconductor die.
- 19. (Currently Amended) A semiconductor device, comprising:
  - a semiconductor die having a first surface and a second surface, the semiconductor die comprising active circuitry within the first surface; and
  - a heat spreader connected to the first surface of the semiconductor die <u>using a die attach</u> layer.
- 20. (Canceled).
- 21. (Original) The semiconductor device of claim 19, wherein the heat spreader is soldered to a metal layer overlying a portion of the first surface of the semiconductor die.
- 22. (Original) The semiconductor device of claim 19, further comprising:
  a second heat spreader underlying the second surface of the semiconductor die.

- 23. (Original) The semiconductor device of claim 22, wherein the first heat spreader provides a first heat dissipation path from the first semiconductor device, and the second heat spreader provides a second heat dissipation path from the first semiconductor device.
- 24. (Original) The semiconductor device of claim 22, further comprising a second semiconductor device underlying the second surface of the semiconductor device and overlying the second heat spreader.
- 25. (Original) The semiconductor device of claim 24, wherein the second surface of the semiconductor device is attached to the second semiconductor device via a first device attach layer, and the second semiconductor device is attached to the second heat spreader via a second device attach layer.